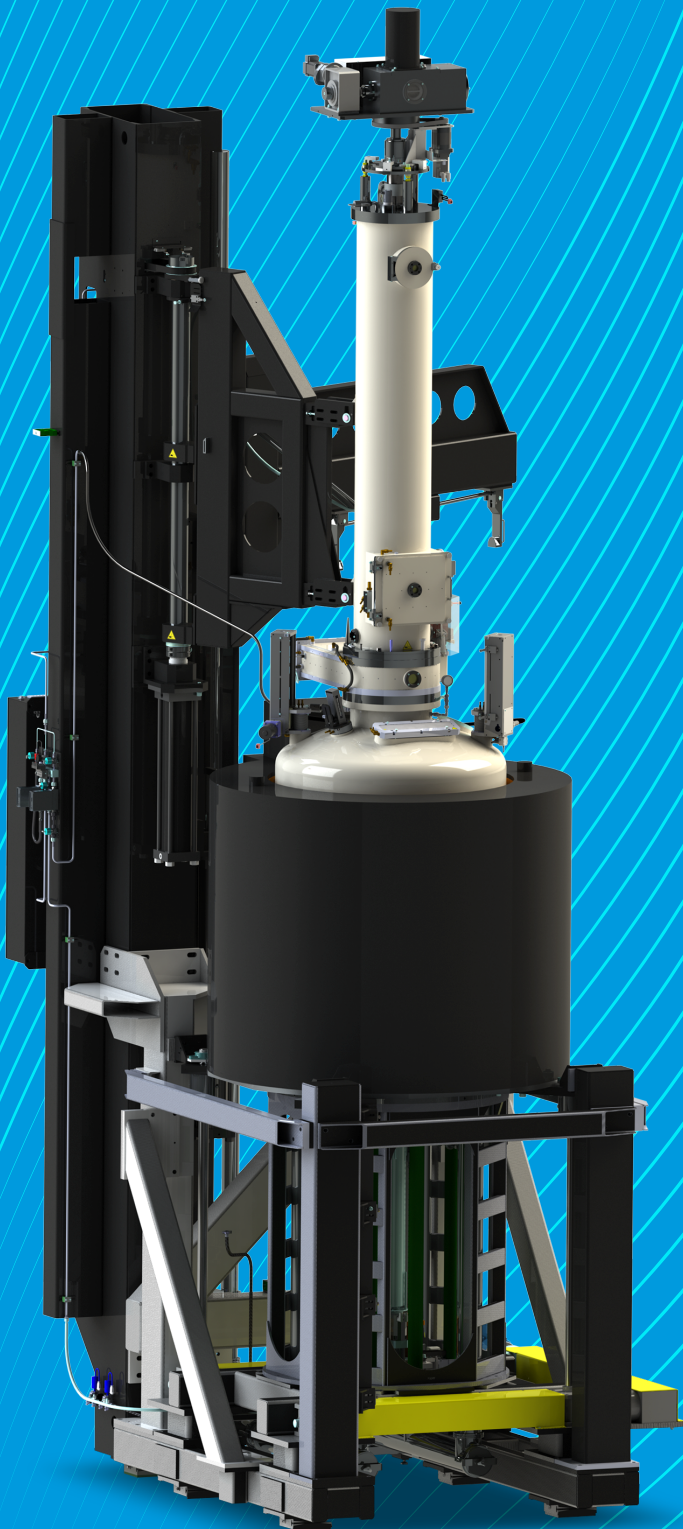


Linton



KX360 MCZR

Semiconductor Crystal Growing Furnace

- Optimized For Large Ingot Growth
- 4000 Gauss Superconducting Magnet
- Advanced Control System
- Low Power Consumption
- Integrated Communications with optional WINGS system
- Complete Customization Available



KX360MCZR

Semiconductor Crystal Growing Furnace

The KX360MCZR has the largest furnace chamber in our semiconductor machine line, 1400 mm in diameter, capable of accommodating 36-inch crucibles. The furnace can produce 300 mm and larger ingots. The KX360MCZR is magnet-ready for resistive and superconducting magnets.

PERFORMANCE

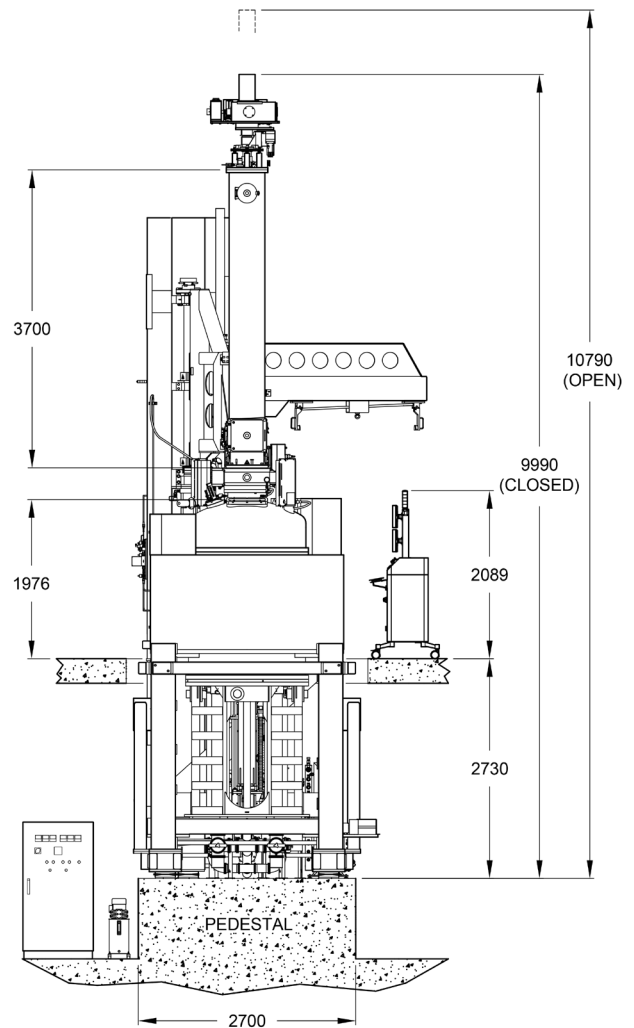
Furnace Chamber Diameter	1400 mm (55.1 in)
Receiving Chamber Height	4500 mm (177.2 in)
Throat Diameter	400 mm (15.7 in)
Seed Lift Rate	0-508 mm/hr
Seed Jog Speed (Nominal)	400 mm/min
Seed Rotation (Reversible)	0-20 rpm
Total Crucible Travel	850mm (33.5 in)
Crucible Lift Rate	0-127 mm/hr
Crucible Jog Speed (Nominal)	127 mm/min
Crucible Rotation (Reversible)	0-12 rpm

SILICON CHARGE CAPACITY

CRUCIBLE DIAMETER*	CHARGE SIZE
32.0 in or 36.0 in	up to 650 kg

OPTIONS & ACCESSORIES

Cooling Tube	Cusp Magnet
Feeders	Vacuum Pumps
Hot Zones	Ingot and Crucible Handling
Filters	Maintenance Tools



Dimensions shown are typical and can be customized to meet customer requirements